







## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

application of:

Mamoru NAKASUJI, et al.

**ATTN: Box Missing Parts** 

Serial No.:

09/891,611

Group Art Unit: Unknown

Filed: June 27, 2001

Examiner:

Unknown

For:

INSPECTION SYSTEM BY CHARGED PARTICLE BEAM AND METHOD OF

MANUFACTURING DEVICES USING THE SYSTEM

## AMENDMENT TRANSMITTAL

Commissioner for Patents Washington, D.C. 20231

October 22, 2001

Sir:

Transmitted herewith is an Amendment in the above-identified application.

The fee has been calculated as shown below:

	CLAIMS AS AMENDED					
	Claims Remaining After Amendment	Highest Number Previously Paid For		Present Extra	Large Entity	Additional Fee
Total Claims	164	20	=	144_	X \$18	\$ 2,592.00
Independent Claims	45	3	=	42	X \$84	\$ 3,528.00
XX First Presentation of Multiple Dependent Claims \$280						\$ 280,00
TOTAL FEES ENCLOSED:						\$ 6,400.00

Enclosed please find our check in the amount of \$6,400.00 for the additional claims fee  $\underline{\mathbf{X}}$ in connection with this amendment. The Commissioner is hereby authorized to charge payment for any additional fees associated with this communication or credit any overpayment to Deposit Account No. <u>01-2340</u>. Two duplicates of this sheet are attached.

Respectfully submitted,

ARMSTRONG, WESTERMAN, HATTORI McLELAND & NAUGHTON, LLP

> William G. Kratz, Jr. Attorney for Applicants

Reg. No. 22,631

Attorney Docket No.: 010817

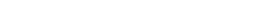
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WGK/sdj









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46/24/2001 SDIRETA1 00000083 09891611

01 FC:103 02 FC:102 03 FC:104

2592.00 OF 3528.00 OF 280.00 OF

PRELIMINARY AMENDMENT

Commissioner for Patents

Washington, D.C. 20231

Date: October 22, 2001

Sir:

Prior to calculation of the filing fee and examination of this application, please amend the above-identified application as follows:

## **IN THE CLAIMS**:

Please amend claims 53, 55, 75 and 81 as follows:

pl

- 53. (Amended) The inspection apparatus of claim 51 or 52 wherein the apparatus is constructed so that an energizing condition of an objective lens is obtained under a state where a pattern on a wafer is electrically charged.
- 55. (Amended) A method for manufacturing semiconductor devices wherein a wafer during a manufacturing process or after processing is evaluated by using the inspection apparatus of any one of claims 51, 52 or 54.